



FPD Materials & Components Japan TC Chapter Meeting Summary and Minutes

SEMI Japan Standards Summer 2015 Meetings Monday 27 July, 2015, 15:00-17:00 SEMI Japan, Tokyo, Japan

Next Committee Meeting SEMI Japan Standards Spring 2015 Meetings Wednesday, November 11, 2015, 15:00-17:30 SEMI Japan, Tokyo, Japan

Table 1 Meeting Attendees

Co-Chairs of FPD M&C Committee: Tadahiro Furukawa (Yamagata University), Yoshi Shibahara (Fujifilm) **SEMI Staff:** Naoko Tejima (SEMI Japan)

Company	Last	First	Company	Last	First
Sumitomo Bakelite	Eguchi	Toshimasa	Corning International	Okamura	Haruo
Ricoh	Fujimura	Koh	SK Electronics	Nogami	Tadakazu
Yamagata University	Furukawa	Tadahiro	Fujifilm	Sato	Tadanobu
Otsuka Electronics	Kawaguchi	Akira	Fujifilm	Shibahara	Yoshi
Nitto Denko	Kobayashi	Shigeo	Japan Barrier Society	Yamagishi	Naomichi
Meiji University	Nagai	Kazukiyo	SEMI Japan	Tejima	Naoko
НОҮА	Nitobe	Kaname			

st alphabetical order by last name

Table 2 Leadership Changes

None.

Table 3 Ballot Results

Passed ballots and line items will be forwarded to the ISC Audit & Review Subcommittee for procedural review. **Failed** ballots and line items were returned to the originating task forces for re-work and re-balloting.

Document #	Document Title	Committee Action
5555	Revision to SEMI D50-0707, Test Method for Surface Hardness of FPD Polarizing Film with title change to: Test Method for Surface Hardness of FPD Components	Failed

Table 4 Authorized Ballots

Document #	When	SC/TF/WG	Details
5555A	,	0	Revision to SEMI D50-0707, Test Method for Surface Hardness of FPD Polarizing Film with title change to: Test Method for Surface Hardness of FPD components

FPD Materials & Components Japan TC Chapter Joint Meeting Minutes





Table 5 Authorized ActivitiesFPD Materials &Components Japan TC Chapter

Document #	Type	SC/TF/WG	Details
-	SNARF (Tentatively)		Test Method of Water Vapor Barrier Property for Plastic Films with High Barrier for Electronic Devices

Table 6 New Action Items

Item #	Assigned to	Details
FPD M&C 150727-01	SEMI Staff	To correct "Naomichi, Yamagishi, Japan <u>Business</u> Society" of "Table 1 Meeting Attendee" of the previous meeting minutes hould be corrected to "Naomichi, Yamagishi, Japan <u>Barrier</u> Society" of the previous meeting minutes.
FPD M&C 150727-02	Polarizing Film Task Force	To rework for Doc.#5555A.
FPD M&C 150727-03	Polarizing Film Task Force	To submit Document #5555A, Revision to SEMI D50-0707, Test Method for Surface Hardness of FPD Polarizing Film with title change to: Test Method for Surface Hardness of FPD components for Cycle 7, 2015.
FPD M&C 150727-04		To send LOI for SNARF, Test Method of Water Vapor Barrier Property for Plastic Films with High Barrier for Electronic Devices, to SEMI by the end of August.
FPD M&C 150727-05	NEMI MAT	To circular the new SNARF to TC members and GCS to get approval before the next Japan TC Chapter meeting (November 11).
FPD M&C 150727-06	Tadahiro Furukawa	To invite a speaker from Taiwan for STEP/Workshop.
FPD M&C 150727-07	SEMI Staff	To check 5 year review documents

1 Welcome, Reminders, and Introductions

Tadahiro Furukawa, committee co-chair, called the meeting to order at 15:00. Self-introductions were made followed by the agenda review.

2 Required Meeting Elements

The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed by SEMI staff, Naoko Tejima.

3 Review of Previous Meeting Minutes

The committee reviewed the minutes of the previous meeting held on April 10, 2015.

It was pointed that "Naomichi, Yamagishi, Japan <u>Business</u> Society" of "Table 1 Meeting Attendee" should be corrected to "Naomichi, Yamagishi, Japan <u>Barrier</u> Society"

Motion: To approve the minutes of the previous meeting as written after the above point is corrected.

By / 2nd: Yoshi Shibahara (Fujifilm) / Shigeo Kobayashi (Nitto Denko)

Discussion: None

Vote: 10 in favor and 0 opposed. Motion passed.

Action Item: SEMI staff to correct "Naomichi, Yamagishi, Japan <u>Business</u> Society" of "Table 1 Meeting Attendee" of the previous meeting minutes hould be corrected to "Naomichi, Yamagishi, Japan <u>Barrier</u> Society" of the previous meeting minutes.

Attachment:01_JA_FPD_M&C_Previous_Mtg_Minutes_150724FPD Materials & Components Japan TC ChapterJoint Meeting Minutes2

July 27, 2015 SEMI Japan Tokyo, Japan





4 SEMI Staff Report

Naoko Tejima gave the SEMI staff report. This report included SEMI Global 2015 Calendar of Events, Global Standards Meeting Schedule, 2015 Critical Dates for SEMI Standards Ballots, SEMI Standards Publications, A&R Ballot Review and Contact Information.

Attachment: 02_SEMI_Staff_Report_150724

5 Liaison Reports

5.1 FPD Metrology Korea TC Chapter Report

Naoko Tejima reported for the FPD Metrology Korea TC Chapter. This report included Leadership, Organization Chart, Meeting Information, Major Updates and Contact Information.

Attachment: 03_KR_FPD_Liaison_Report_150724

5.2 FPD Metrology Taiwan TC Chapter Report

Naoko Tejima reported for the FPD Metrology Taiwan TC Chapter. This report included Leadership, FPD Standard Committee Organization Chart, FPD Standard Committee Highlights, FPD Committee Meeting Information and Contact Information.

Attachment: 04_TW_FPD_Liaison Report_150206

6 Ballot Review

6.1 Doc.#5555, Revision to SEMI D50-0707, Test Method for Surface Hardness of FPD Polarizing Film with title change to: Test Method for Surface Hardness of FPD components.

This document failed committee review.

Action Item: Polarizing Film Task Force to rework for Doc.#5555A.

Attachment: 05_Ballot_Report_for_5555_150724

7 Task Force Reports

7.1 Polarizing Film Task Force

Yoshi Shibahara reported for the ballot results of Doc.#5555. Of note:

- *Doc.#5555*, Revision to SEMI D50-0707, Test Method for Surface Hardness of FPD Polarizing Film with title change to: Test Method for Surface Hardness of FPD components, *failed* committee review as previously discussed. (See 7) and it will be reworked by TF.
- Motion: To approve to submit Document #5555A Revision to SEMI D50-0707, Test Method for Surface Hardness of FPD Polarizing Film with title change to: Test Method for Surface Hardness of FPD components for Cycle 7, 2015.

By / 2nd: Yoshi Shibahara (Fujifilm) / Shigeo Kobayashi (Nitto Denko)

Discussion: None.

Vote: 10 in favor and 0 opposed. Motion passed.

Shigeo Kobayashi, Nitto Denko reported for discussion about the Measuring Method of Polarizing Film Configuration.

Action Item: Polarizing Film Task Force to submit *Document #5555A*, *Revision to SEMI D50-0707*, *Test Method for Surface Hardness of FPD Polarizing Film with title change to: Test Method for Surface Hardness of FPD components* for Cycle 7, 2015.

Attachment: 06_Polarizing _Film_TF_Report_150727

FPD Materials & Components Japan TC Chapter Joint Meeting Minutes





7.2 Flexible Display Task Force

Tadahiro Furukawa reported on progress for the Flexible Display Task Force. The Task Force met earlier in the day. Of note:

- New SNARF, Test Method of Water Vapor Barrier Property for Plastic Films with High Barrier for Electronic Devices, was presented for the replace of Doc.#5551, New Standard: Test Method for Measurement of Water Vapor Transmission Rate for Plastic Films and Sheets with High Barrier Properties for Electronic Devices, since its scope will be widen and the number will be newly published.
- The Patented Technologies are included to this document and LOI will be submitted to the TF by the patent holder by the end of August.
- **Motion:** To approve tentatively new SNARF, Test Method of Water Vapor Barrier Property for Plastic Films with High Barrier for Electronic Devices (replaced Doc.#5551)

By / 2nd: Yoshi Shibahara (Fujifilm) / Shigeo Kobayashi (Nitto Denko)

Discussion: None.

Vote: 10 in favor and 0 opposed. Motion passed.

Action Item: Toshimasa Eguchi, Sumitomo Bakelite to send LOI for SNARF, Test Method of Water Vapor Barrier Property for Plastic Films with High Barrier for Electronic Devices, to SEMI by the end of August.

Action Item: SEMI to circular the new SNARF to TC members and GCS to get approval before the next Japan TC Chapter meeting (November 11).

Attachment: 07_New_SNARF_of_Water_Vapor_Barrier_Property_150727

Attachment: 08_Report_of_Flexible_Display_TF_150727

7.3 Color Filter Task Force

Tadahiro Furukawa reported for the Color Filter Task Force that there were no particular things should be reported. Future direction (Continue? or Disband?) will be discussed at the next TF meeting.

7.4 FPD Mask Task Force

Kaname Nitobe reported for the FPD Mask Task Force that there were no particular things should be reported.

8 Old Business

8.1 Previous Meeting Action Items

Naoko Tejima reviewed the previous meeting action items.

Table 7 Previous Meeting Actions Items

Item #	Assigned to	Details
FPD M&C 150206-03	SEMI Staff	To forward adjudication result of Doc.#5796 to the ISC A&R Subcommittee for procedural review Close
FPD M&C 150206-04	SEMI Staff	To forward adjudication result of Doc.#5797 to the ISC A&R Subcommittee for procedural review Close
FPD M&C 150206-05	SEMI Staff	To forward adjudication result of Doc.#5798 to the ISC A&R Subcommittee for procedural review Close
FPD M&C 150206-06	SEMI Staff	To forward adjudication result of Doc.#5799 to the ISC A&R Subcommittee for procedural review Close
FPD M&C 150410-01	Polarizing Film TF	To submit the ballot of SEMI D50 (#5555) for Cycle 5, 2015 Close
FPD M&C 150410-02		To check whether there are the existences of the patented technology in the Doc. 5551, and to discuss a way not to include the patented technologies Close
FPD M&C 150410-03	1 2	To submit the new SNARF of Doc. #5551 3-week before the next Japan TC Chapter meeting (by July 6) Close

FPD Materials & Components Japan TC Chapter Joint Meeting Minutes July 27, 2015 SEMI Japan Tokyo, Japan





9 New Business

9.1 Having STEP/Workshop in future

Coordination Group is planning to hold FPD STEP/Workshop;

- Date: April, 2016 (tentative)
- Venue: Room1-2, SEMI Japan
- Purpose: To promote and activate SEMI Standards activities.
- Agenda (proposal)

13:00-13:10 Introduction 13:10-13:50 Keynote Speech 13:50-14:20 Presentation 1, Current Status of Taiwan Standard Activities 14:20-14:50 Presentation 2, Standard report: Development of Flexible Display 15:00-15:30 Presentation 3, Standard report: Barriers 15:30-16:00 Presentation 4, Standard report: Polarizing Film 16:00-16:30 Presentation 5, Standard report: Mask 16:30-17:00 Presentation 6, Standard report: Metrology

Action Item: Tadahiro Furukawa to invite a speaker from Taiwan.

10 Action Item Review

10.1 New Action Items

Naoko Tejima reviewed the new action items. These can be found in the New Action Items table at the beginning of these minutes.

11 Next Meeting and Adjournment

The next meeting of the FPD Materials & Components Japan TC Chapter and the FPD Metrology Japan TC Chapter Joint Meeting will be decided in a few days.

(After the meeting, it is scheduled for Wednesday, November 11, 2015, 15:00-17:30, SEMI Japan, Tokyo, Japan)





Respectfully submitted by: Naoko Tejima Manager, Standards SEMI Japan Phone: +81.3.3222.5804 Email: ntejima@semi.org

Minutes approved by:

Tadahiro Furukawa (Yamagata University), Co-chair of FPD Materials & Components Japan TC Chapter	Nov. 11, 2015
Yoshi Shibahara (Fujifilm), Co-chair of FPD Materials & Components Japan TC Chapter	Nov. 11, 2015

Table 8 Index of Available Attachments #1

#	Title	
1	JA_FPD_M&C_Previous_Mtg_Minutes_150727	
2	SEMI_Staff_Report_150727	
3	KR_FPD_Liaison_Report_150727	
4	TW_FPD_Liaison_Report_150727	
5	Ballot_Report_for_5555_150727	
6	Polarizing_Film_TF_Report_150727	
7	New_SNARF_of_Water_Vapor_Barrier_Property_150727	
8	Flexible_Display_TF_Report_150727	

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact Naoko Tejima at the contact information above.